

Non-contact Wafer Sorting System



NC-3000R

- High speed and clean wafer robot
- Non-contact measurement for resistivity, thickness and P/N type of silicon wafers
- High precision and high stability measurement
- Standard 7 cassette stations for loader/unloader (CCW rotary mechanism)
- Wafer sizes : 12"φ (or 6"φ and 8"φ)
- Flatness (Bow/Warp/TTV) measurement (option)

DIMENSIONS

2,000 (W) × 2,000 (D) × 1,600 (H) mm, 1,000kg
(FL : 1,000mm)

UTILITIES

Power supply : *Select from 100~240V, 50/60Hz, 2kVA
Vacuum : -86kPa
CDA (or N₂) : 0.7MPa (7.0kgf/cm²) with air regulator



NC-80T

- High precision and high speed silicon wafer thickness sorting system with non-contact electric static capacitance probe / meter
- 1 point / 5 points measurement (option : 9 points and more)
- High tact 9 seconds / 5 points / wafer
- Measuring accuracy : ±0.3 μm
- Resolution : 0.1 μm
- The number of cassettes on loader and unloader is designed by specifications

DIMENSIONS

2,150 (W) × 1,200 (D) × 1,100 (H) mm, 1,000kg
(in case of 6"φ, and loader × 5 / unloader × 6 cassettes)

UTILITIES

Power supply : *Select from 100~240V, 50/60Hz, 2kVA
Vacuum : -86kPa
CDA (or N₂) : 0.7MPa (7.0kgf/cm²) with air regulator